

# Lecture 0: Introduction

# Learning Objectives

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At the end of this lecture, you should be able to

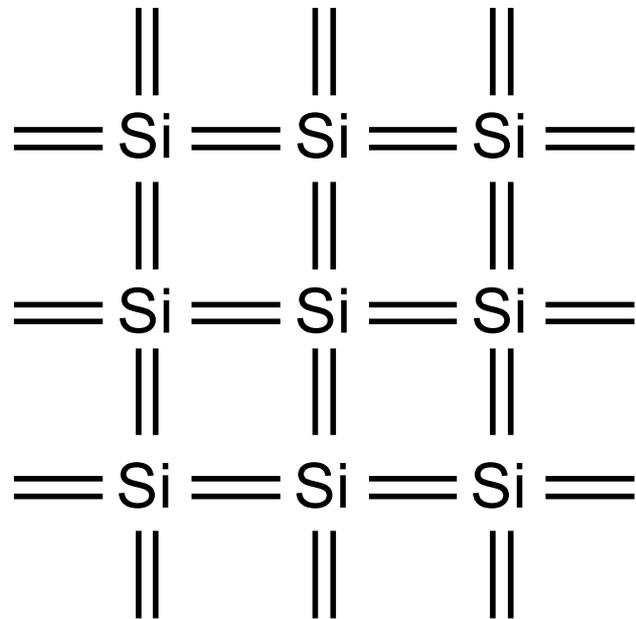
- Define CMOS VLSI Design
- Explain the behavior of CMOS transistors as digital switches
- Design logic gates using transistors
- Sketch cross-sections of transistors and logic gates
- Describe the masks and steps used to fabricate a CMOS circuit

# Introduction

- ❑ Integrated circuits: many transistors on one chip.
- ❑ *Very Large Scale Integration* (VLSI): bucketloads!
- ❑ *Complementary Metal Oxide Semiconductor*
  - Fast, cheap, low power transistors
- ❑ Today: How to build your own simple CMOS chip
  - CMOS transistors
  - Building logic gates from transistors
  - Transistor layout and fabrication
- ❑ Rest of the course: How to build a good CMOS chip

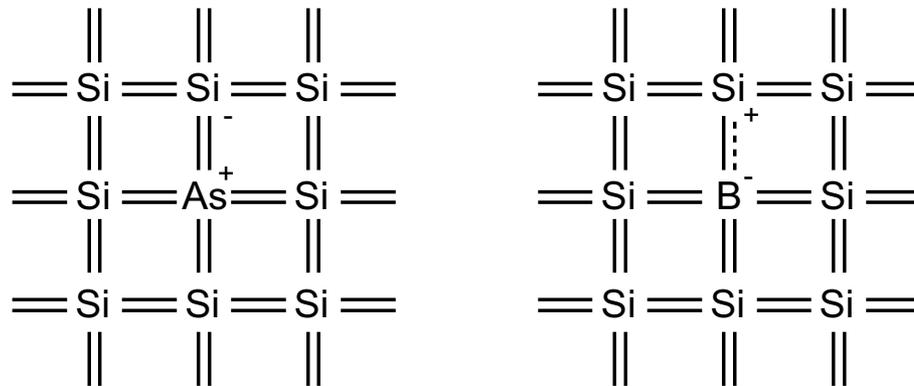
# Silicon Lattice

- ❑ Transistors are built on a silicon substrate
- ❑ Silicon is a Group IV material
- ❑ Forms crystal lattice with bonds to four neighbors



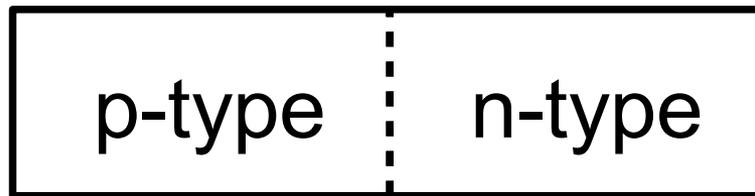
# Dopants

- ❑ Silicon is a semiconductor
- ❑ Pure silicon has no free carriers and conducts poorly
- ❑ Adding dopants increases the conductivity
- ❑ Group V: extra electron (n-type)
- ❑ Group III: missing electron, called hole (p-type)



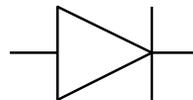
# p-n Junctions

- ❑ A junction between p-type and n-type semiconductor forms a diode.
- ❑ Current flows only in one direction



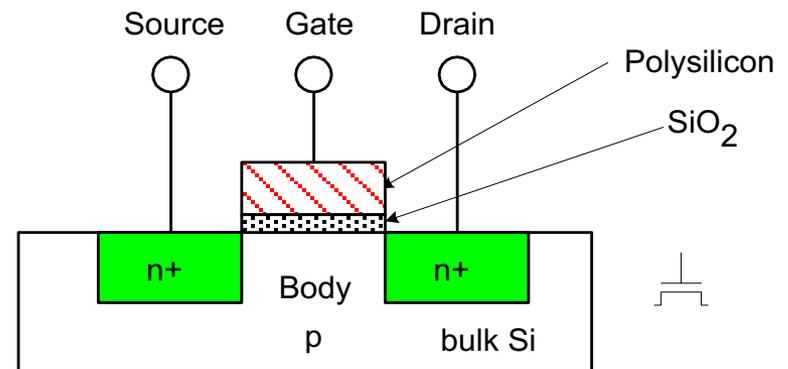
anode

cathode



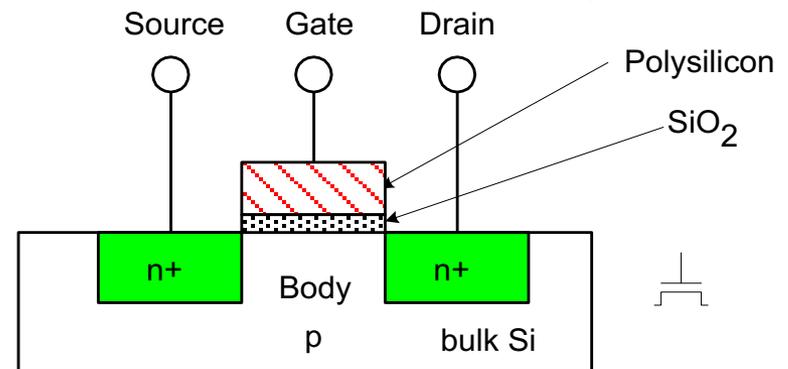
# nMOS Transistor

- ❑ Four terminals: gate, source, drain, body
- ❑ Symbol shows gate, source, drain
  - Usually omits body
  - Source and drain are logically indistinguishable



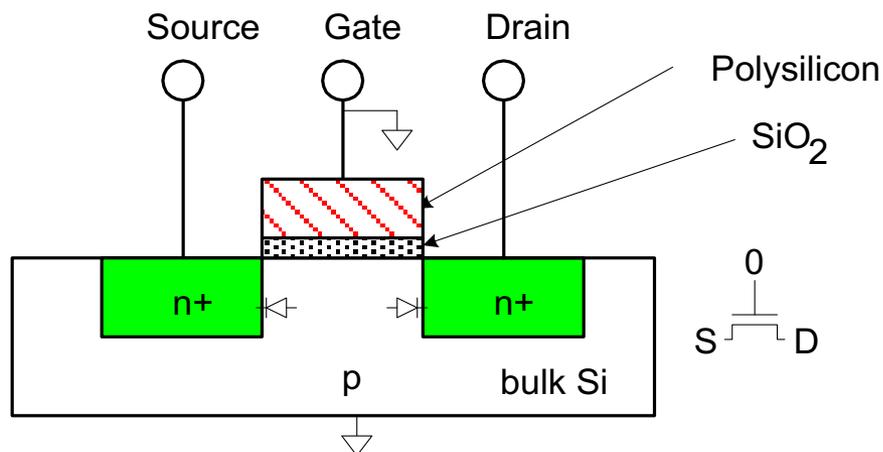
# nMOS Transistor

- ❑ Gate – oxide – body stack looks like a capacitor
  - Gate and body are conductors
  - Body is lightly doped p-type
  - Gate is metal or polycrystalline silicon (polysilicon)
  - $\text{SiO}_2$  (oxide) is an excellent insulator
  - Called metal – oxide – semiconductor (MOS) capacitor
- ❑ Source and drain are heavily doped ( $n^+$ ) silicon



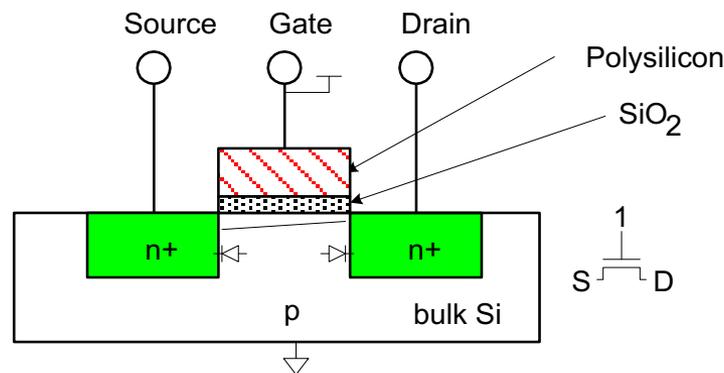
# nMOS Operation

- ❑ Body is usually tied to ground (0 V)
- ❑ When the gate is at a low voltage:
  - P-type body is at low voltage
  - Source-body and drain-body diodes are OFF
  - No current flows, transistor is OFF



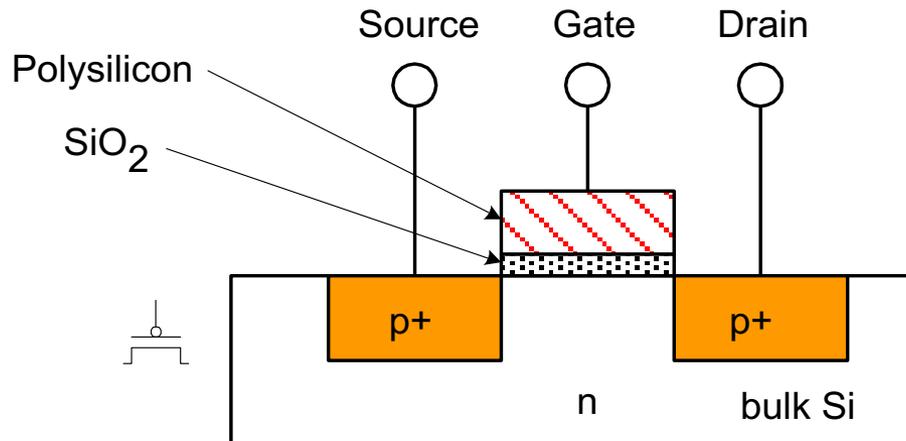
# nMOS Operation Cont.

- When the gate is at a high voltage:
  - Positive charge on gate of MOS capacitor
  - Negative charge attracted to body
  - Inverts a channel under gate to n-type
  - Now current can flow through n-type silicon from source through channel to drain, transistor is ON



# pMOS Transistor

- ❑ Similar, but doping and voltages reversed
  - Body tied to high voltage ( $V_{DD}$ )
  - Gate low: transistor ON
  - Gate high: transistor OFF
  - Bubble indicates inverted behavior

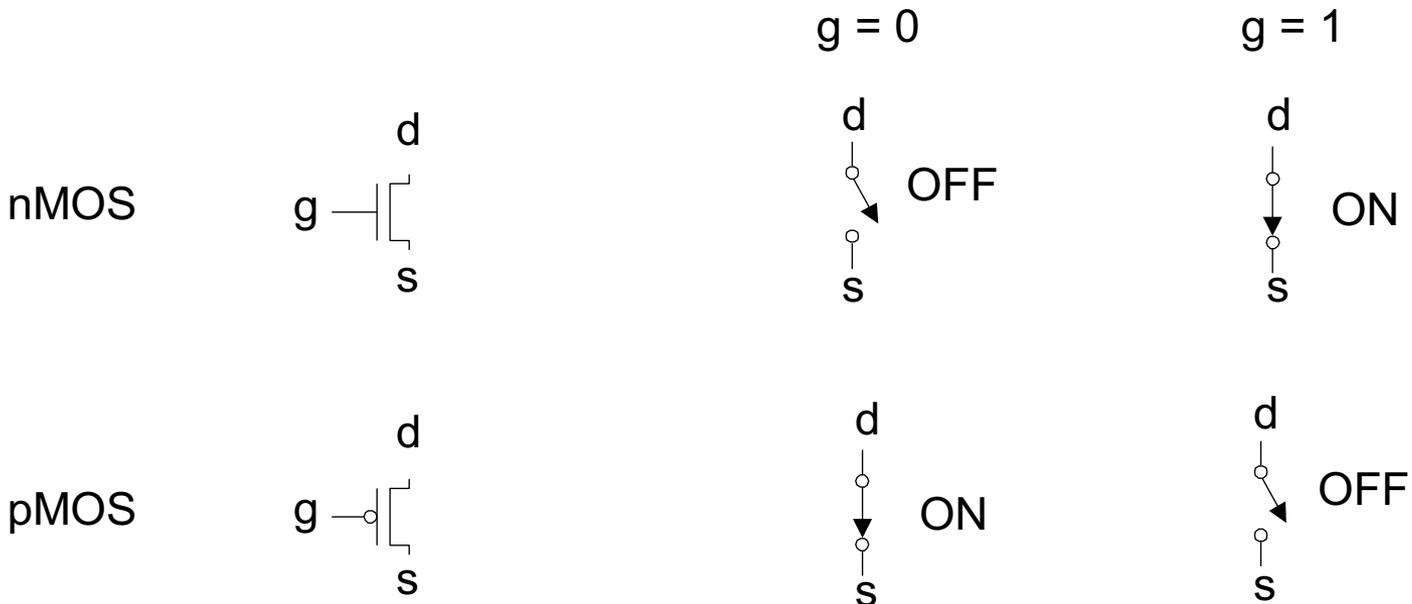


# Power Supply Voltage

- ❑  $GND = 0\text{ V}$
- ❑ In 1980's,  $V_{DD} = 5\text{V}$
- ❑  $V_{DD}$  has decreased in modern processes
  - High  $V_{DD}$  would damage modern tiny transistors
  - Lower  $V_{DD}$  saves power
- ❑  $V_{DD} = 3.3, 2.5, 1.8, 1.5, 1.2, 1.0, 0.8, 0.7, \dots$ 
  - Gradually scaling down as transistors shrink

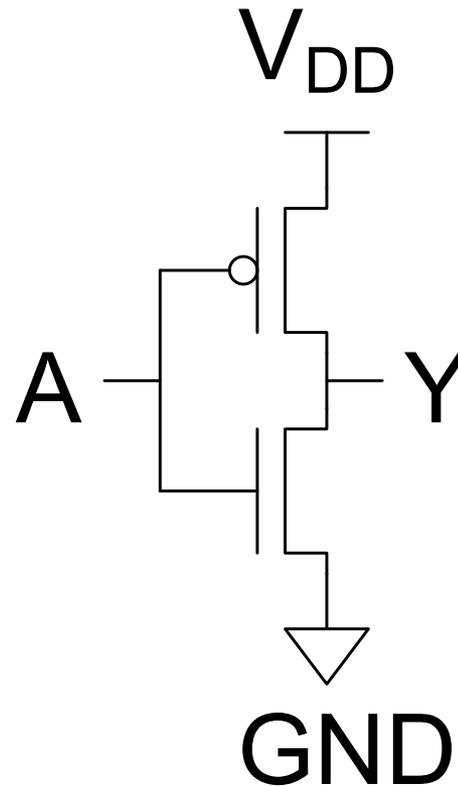
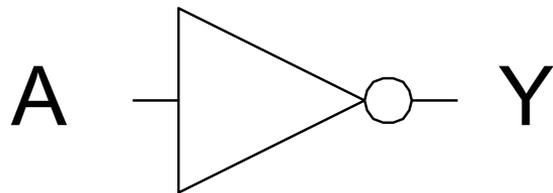
# Transistors as Switches

- ❑ We can view MOS transistors as electrically controlled switches
- ❑ Voltage at gate controls path from source to drain



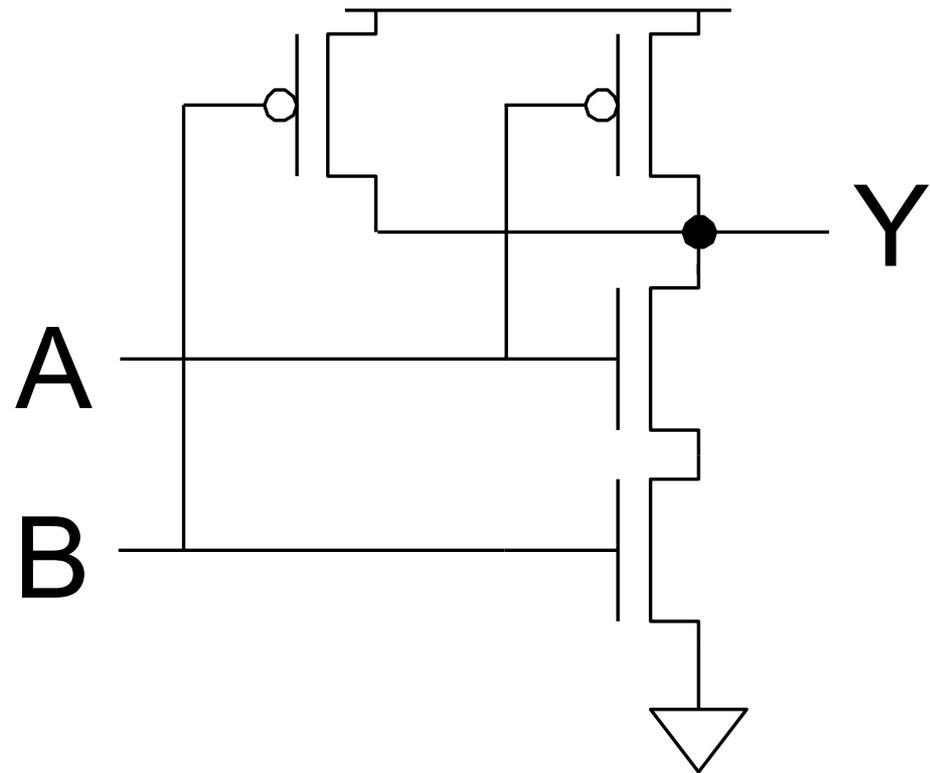
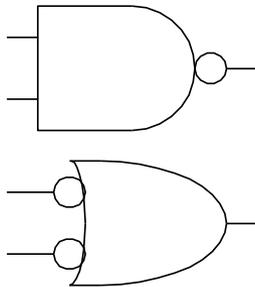
# CMOS Inverter

A	Y



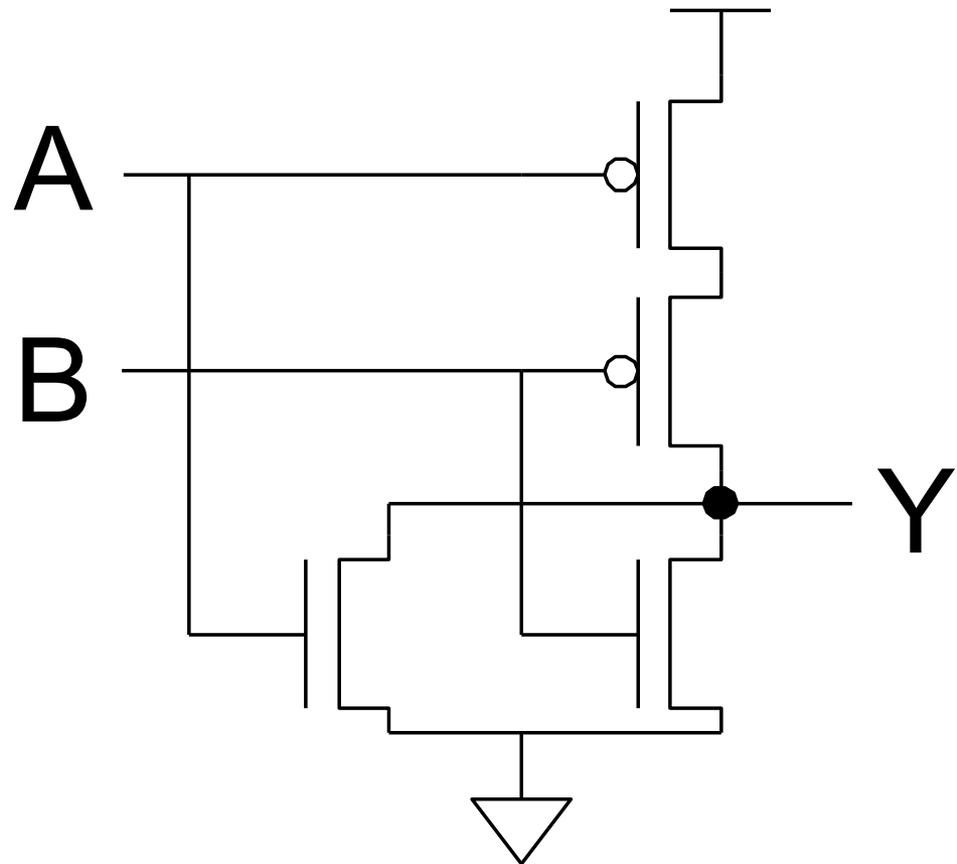
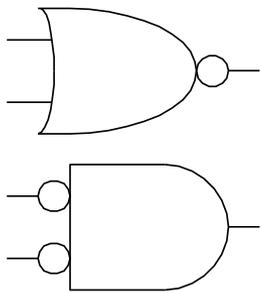
# CMOS NAND Gate

A	B	Y
0	0	
0	1	
1	0	
1	1	



# CMOS NOR Gate

A	B	Y
0	0	1
0	1	0
1	0	0
1	1	0



# 3-input NAND Gate

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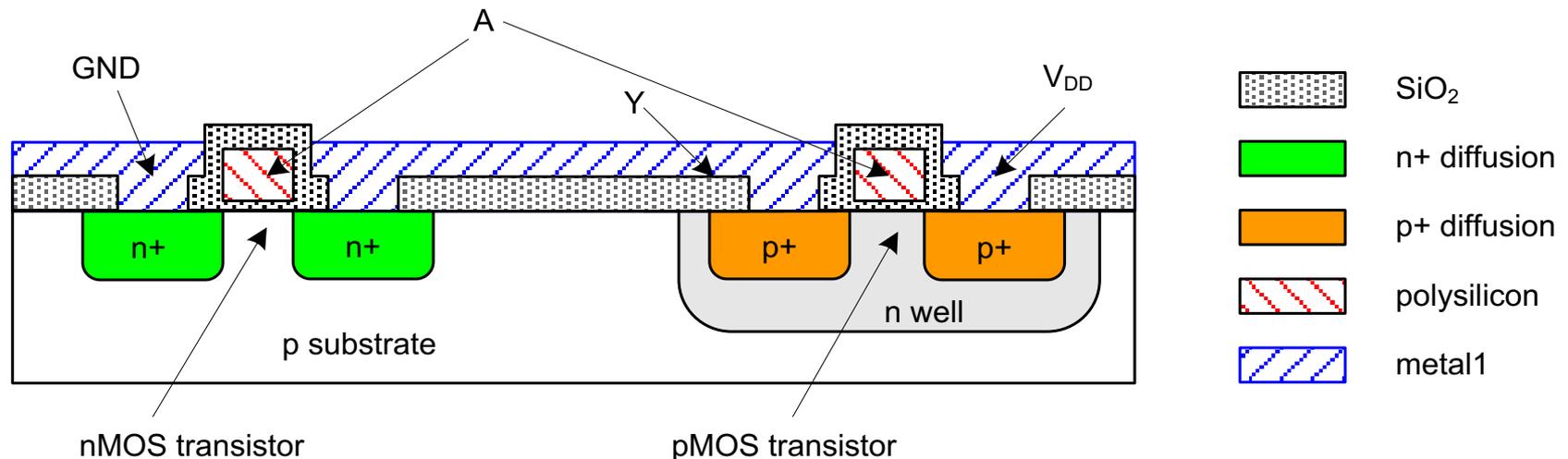
- Y pulls low if ALL inputs are 1
- Y pulls high if ANY input is 0

# CMOS Fabrication

- ❑ CMOS transistors are fabricated on silicon wafer
- ❑ Lithography process similar to printing press
- ❑ On each step, different materials are deposited or etched
- ❑ Easiest to understand by viewing both top and cross-section of wafer in a simplified manufacturing process

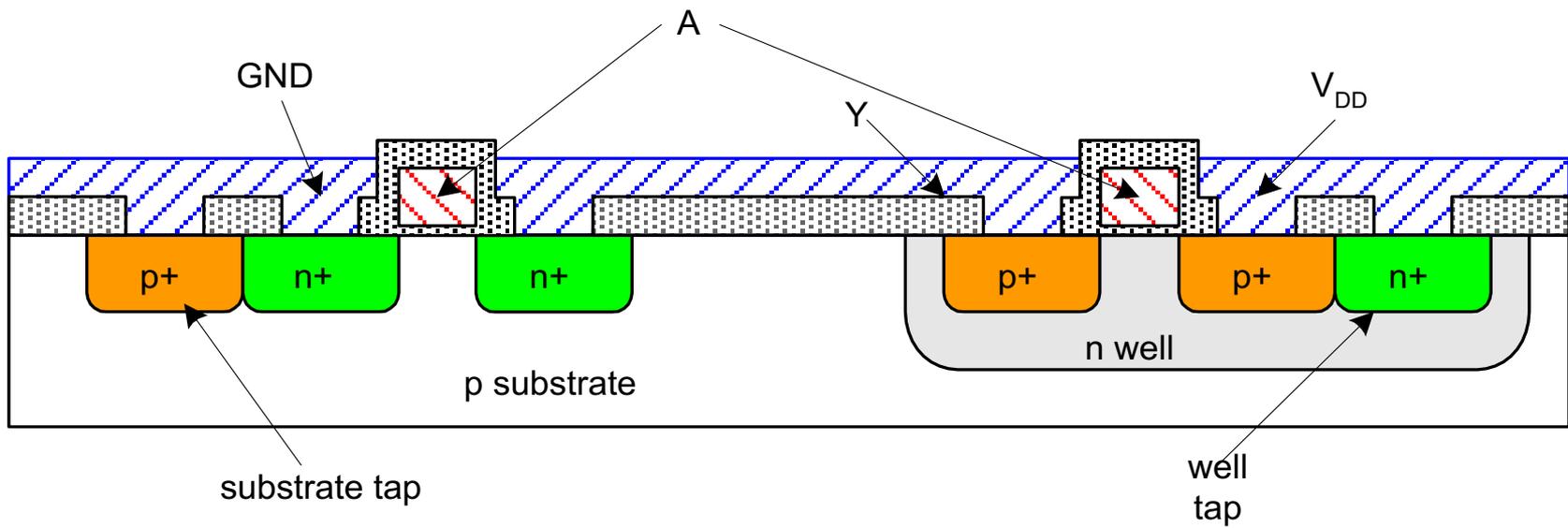
# Inverter Cross-section

- ❑ Typically use p-type substrate for nMOS transistors
- ❑ Requires n-well for body of pMOS transistors
  - So pMOS p-type source/drain doesn't short to p-type substrate



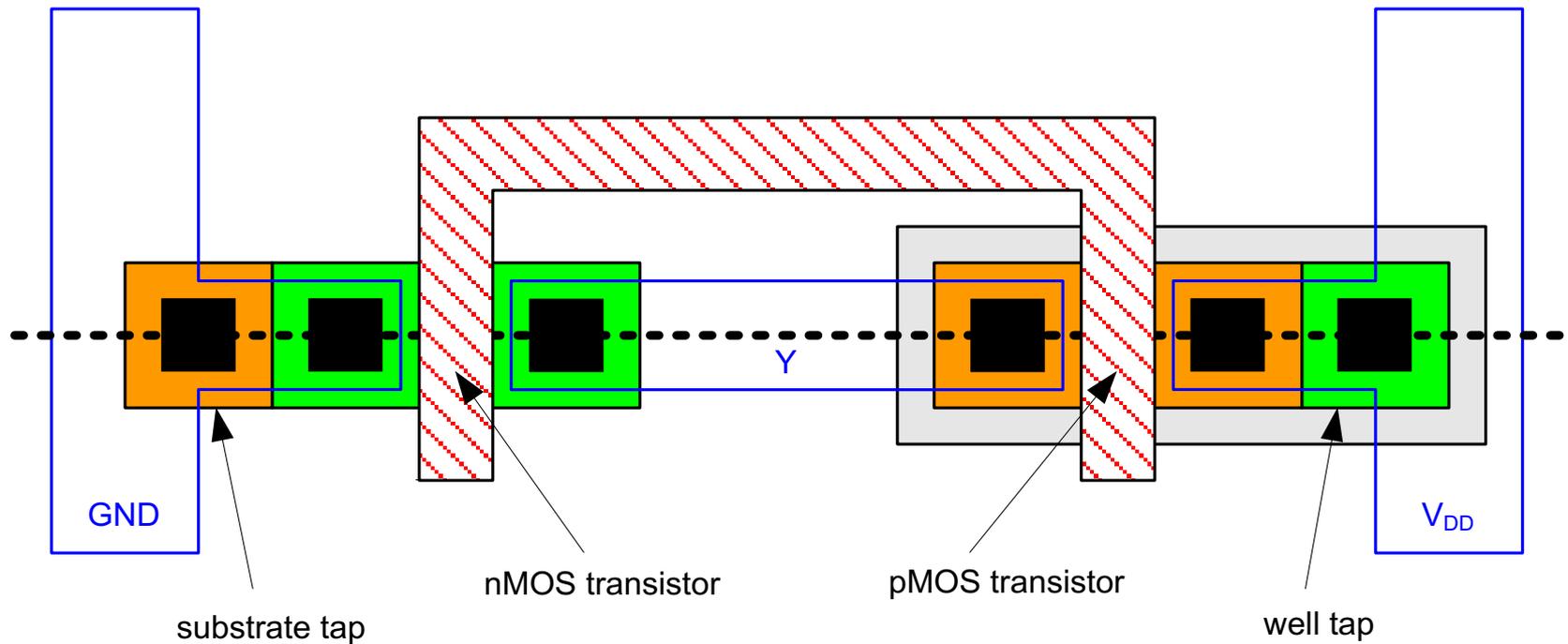
# Well and Substrate Taps

- ❑ Substrate must be tied to GND and n-well to  $V_{DD}$
- ❑ Metal to lightly-doped semiconductor forms poor connection called Schottky Diode
- ❑ Use heavily doped well and substrate contacts / taps



# Inverter Mask Set

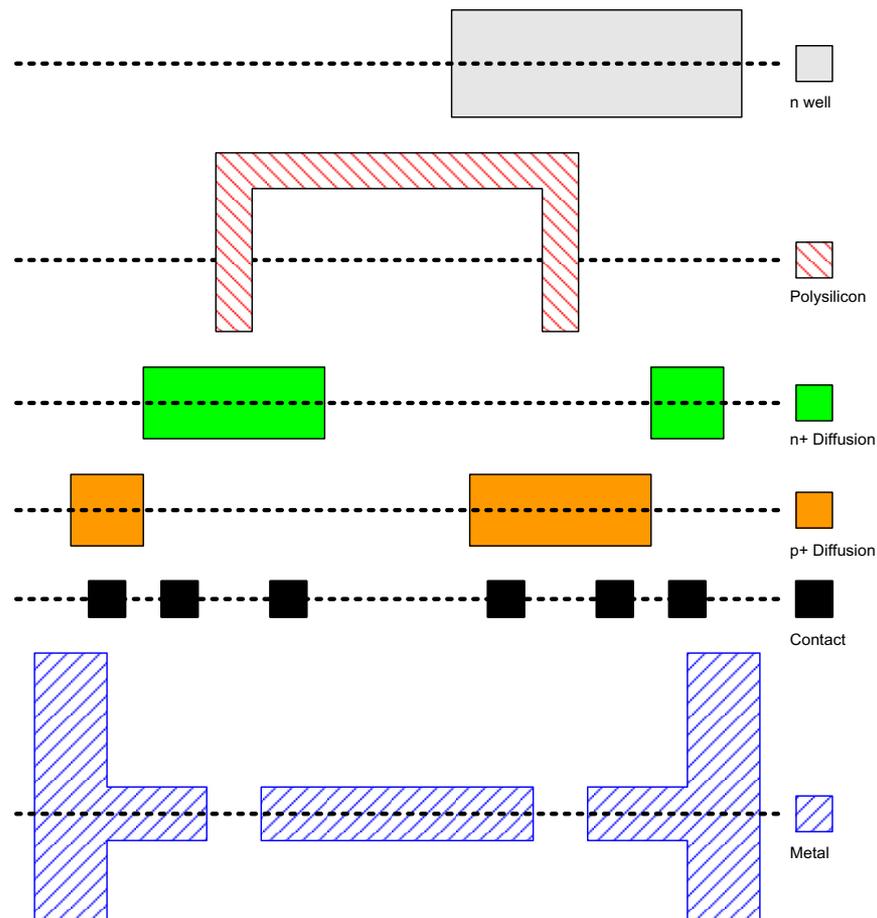
- ❑ Transistors and wires are defined by *masks*
- ❑ Cross-section taken along dashed line



# Detailed Mask Views

## □ Six masks

- n-well
- Polysilicon
- n+ diffusion
- p+ diffusion
- Contact
- Metal



# Fabrication

- ❑ Chips are built in huge factories called fabs
- ❑ Contain clean rooms as large as football fields, costing billions of dollars



Courtesy of International  
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# Fabrication Steps

- ❑ Start with blank wafer
- ❑ Build inverter from the bottom up
- ❑ First step will be to form the n-well
  - Cover wafer with protective layer of  $\text{SiO}_2$  (oxide)
  - Remove layer where n-well should be built
  - Implant or diffuse n dopants into exposed wafer
  - Strip off  $\text{SiO}_2$

p substrate

# Oxidation

- Grow  $\text{SiO}_2$  on top of Si wafer
  - 900 – 1200 C with  $\text{H}_2\text{O}$  or  $\text{O}_2$  in oxidation furnace



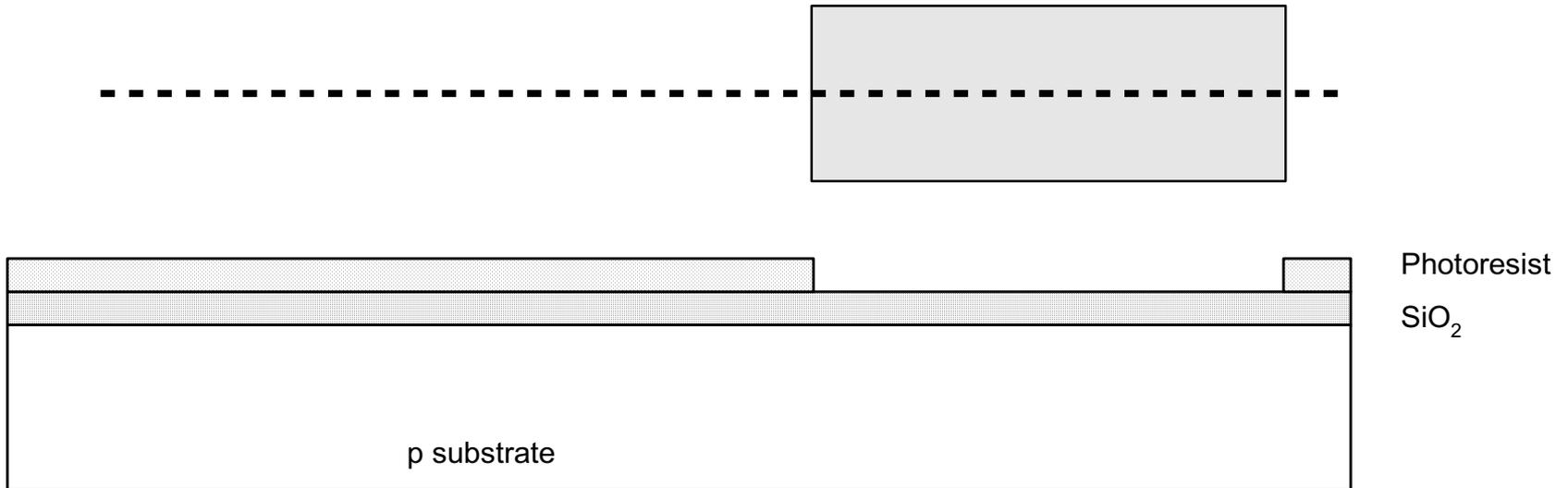
# Photoresist

- Spin on photoresist
  - Photoresist is a light-sensitive organic polymer
  - Softens where exposed to light



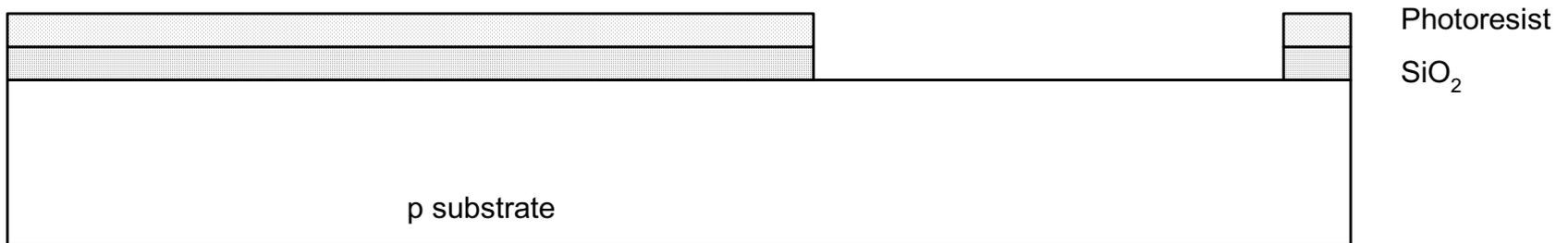
# Lithography

- ❑ Expose photoresist through n-well mask
- ❑ Strip off exposed photoresist



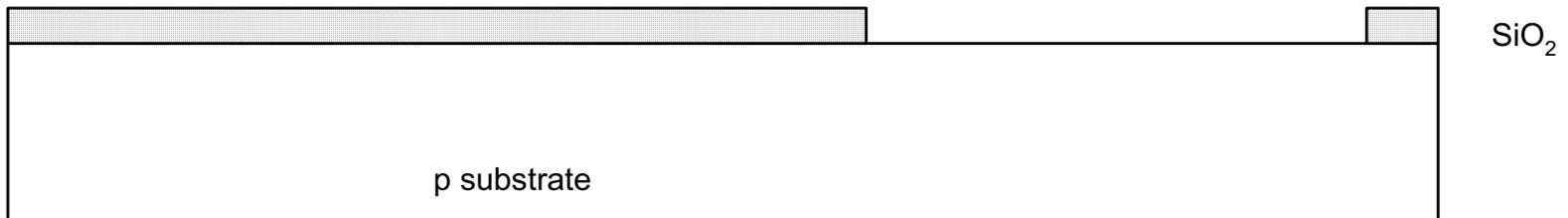
# Etch

- ❑ Etch oxide with hydrofluoric acid (HF)
  - Seeps through skin and eats bone; nasty stuff!!!
- ❑ Only attacks oxide where resist has been exposed



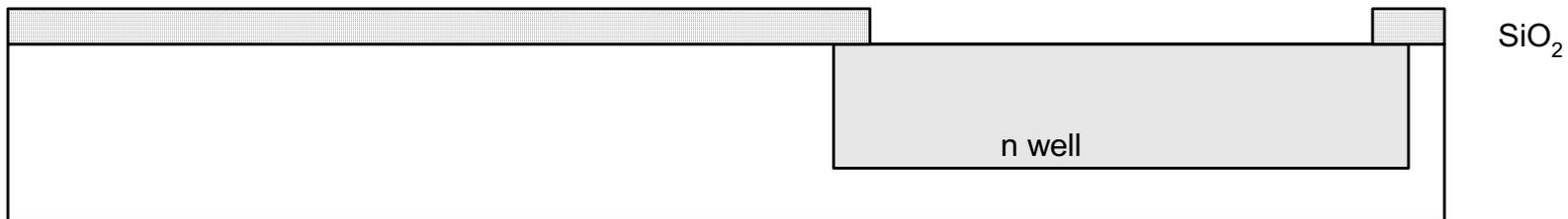
# Strip Photoresist

- ❑ Strip off remaining photoresist
  - Use mixture of acids called piranha etch
- ❑ Necessary so resist doesn't melt in next step



# n-well

- ❑ n-well is formed with diffusion or ion implantation
- ❑ Diffusion
  - Place wafer in furnace with arsenic gas
  - Heat until As atoms diffuse into exposed Si
- ❑ Ion Implantation
  - Blast wafer with beam of As ions
  - Ions blocked by  $\text{SiO}_2$ , only enter exposed Si



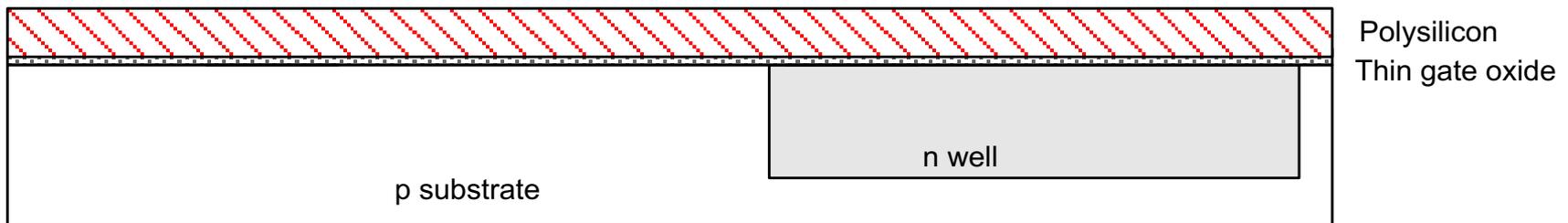
# Strip Oxide

- ❑ Strip off the remaining oxide using HF
- ❑ Back to bare wafer with n-well
- ❑ Subsequent steps involve similar series of steps



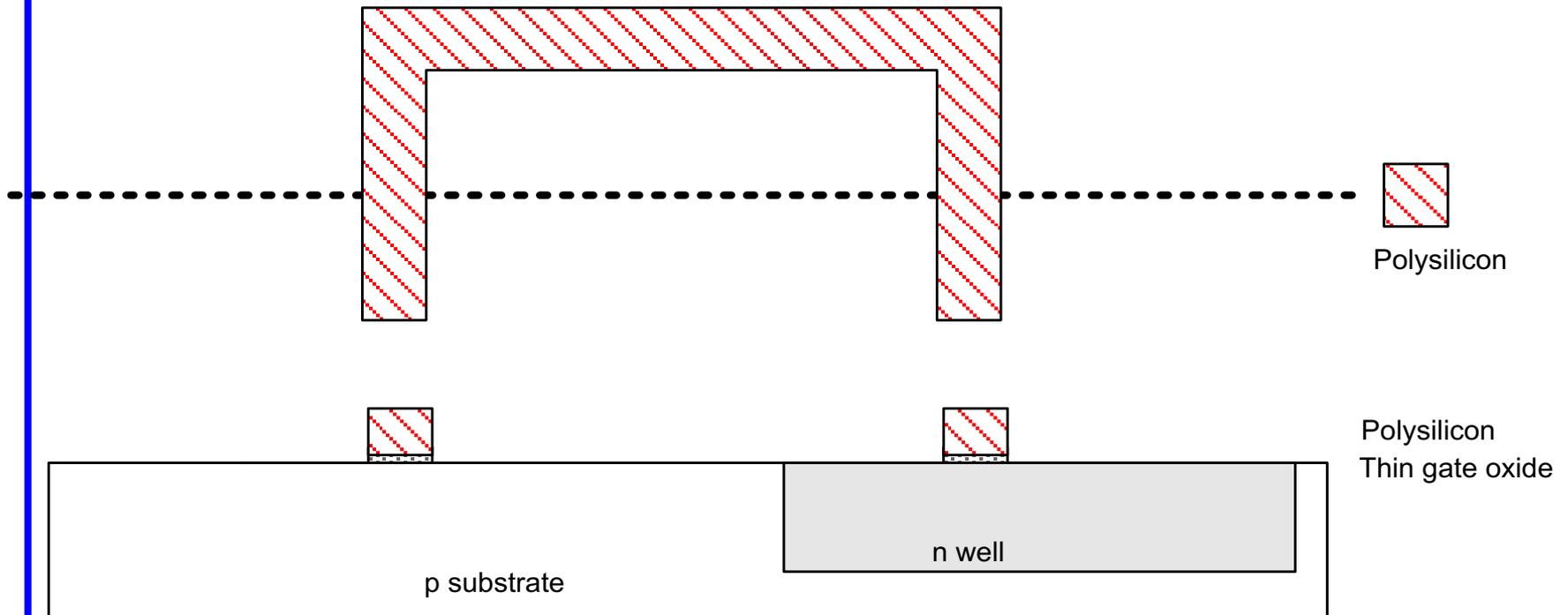
# Polysilicon

- ❑ Deposit very thin layer of gate oxide
  - $< 20 \text{ \AA}$  (6-7 atomic layers)
- ❑ Chemical Vapor Deposition (CVD) of silicon layer
  - Place wafer in furnace with Silane gas ( $\text{SiH}_4$ )
  - Forms many small crystals called polysilicon
  - Heavily doped to be good conductor



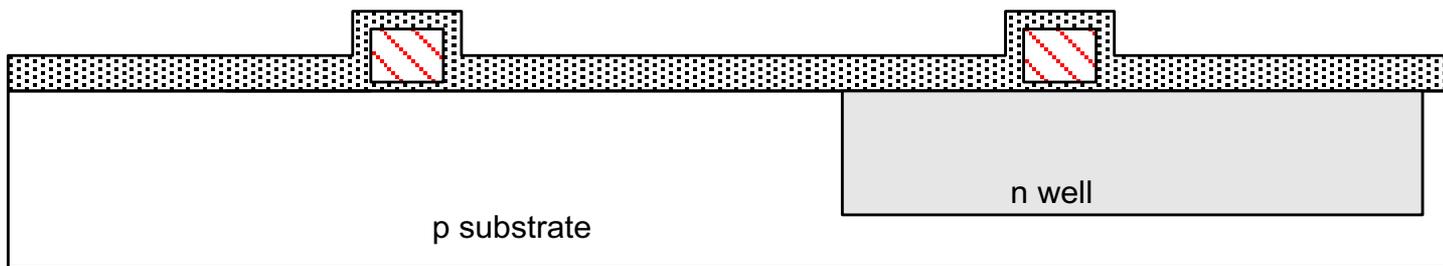
# Polysilicon Patterning

- Use same lithography process to pattern polysilicon



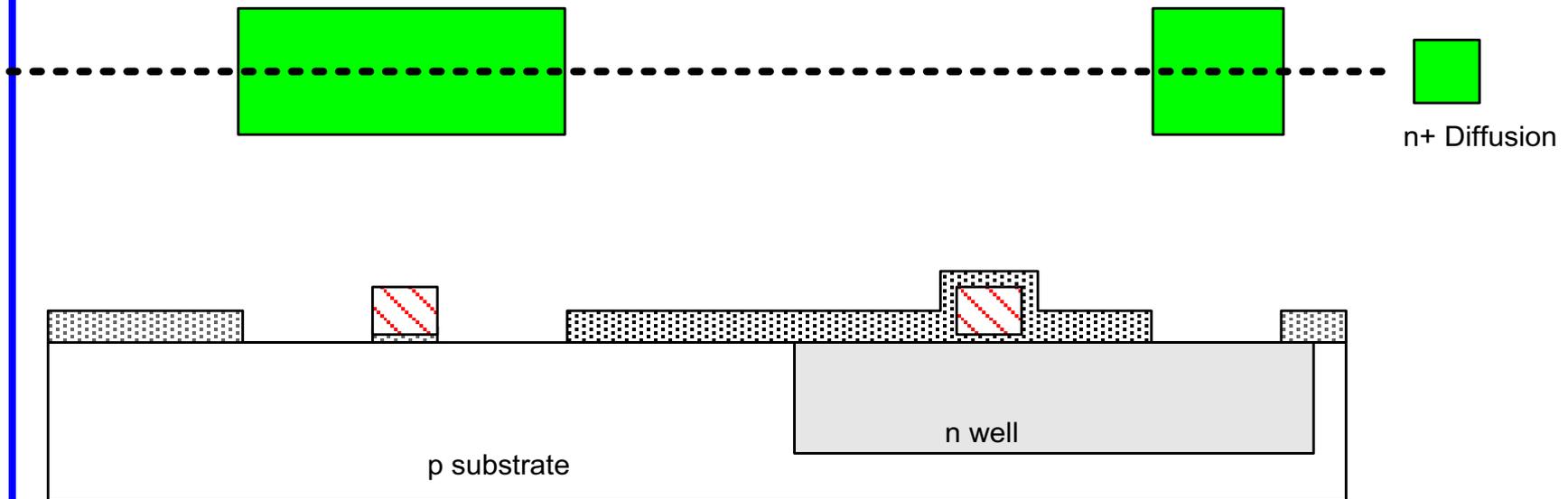
# Self-Aligned Process

- ❑ Use oxide and masking to expose where n+ dopants should be diffused or implanted
- ❑ N-diffusion forms nMOS source, drain, and n-well contact



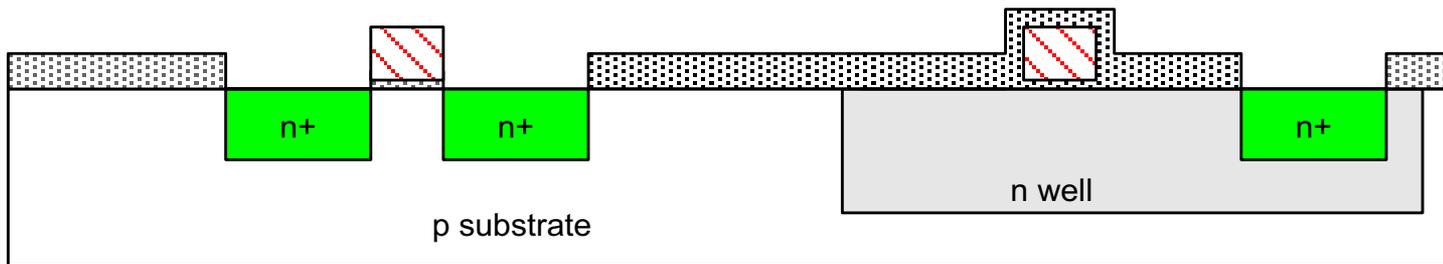
# N-diffusion

- ❑ Pattern oxide and form n+ regions
- ❑ *Self-aligned process* where gate blocks diffusion
- ❑ Polysilicon is better than metal for self-aligned gates because it doesn't melt during later processing



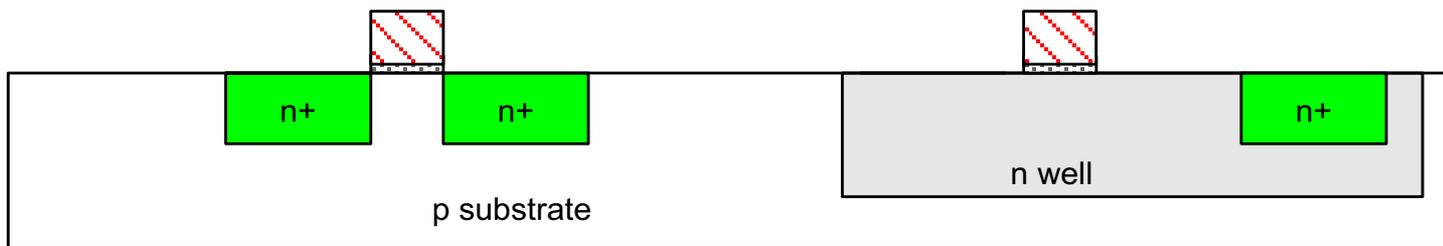
# N-diffusion cont.

- ❑ Historically dopants were diffused
- ❑ Usually ion implantation today
- ❑ But regions are still called diffusion



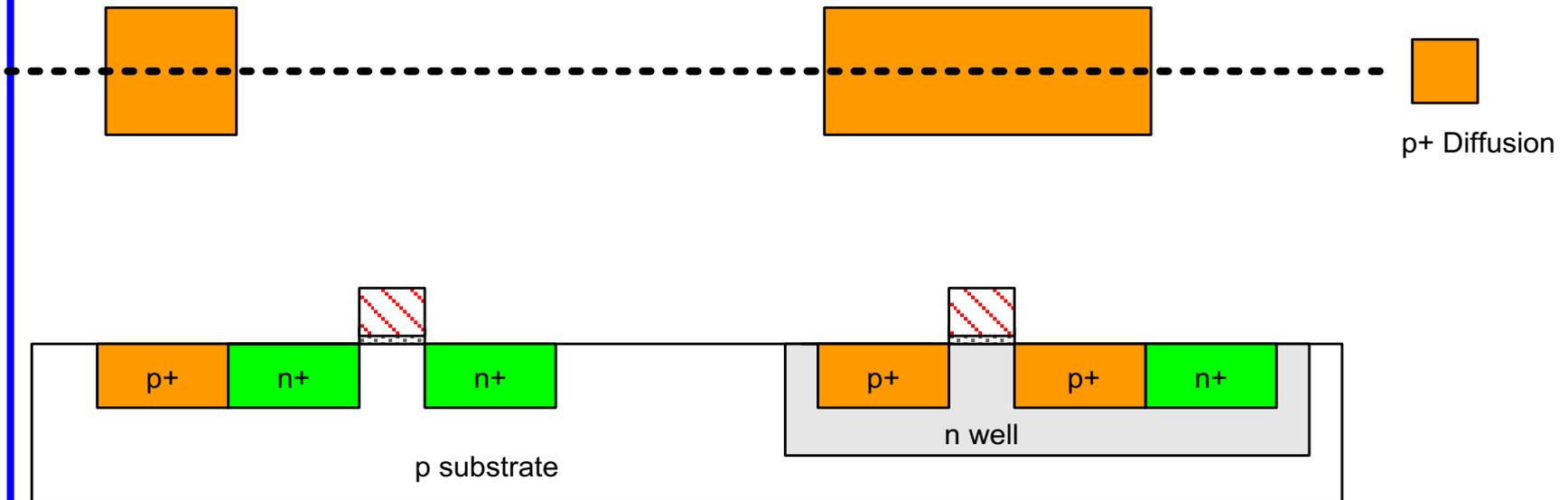
# N-diffusion cont.

- Strip off oxide to complete patterning step



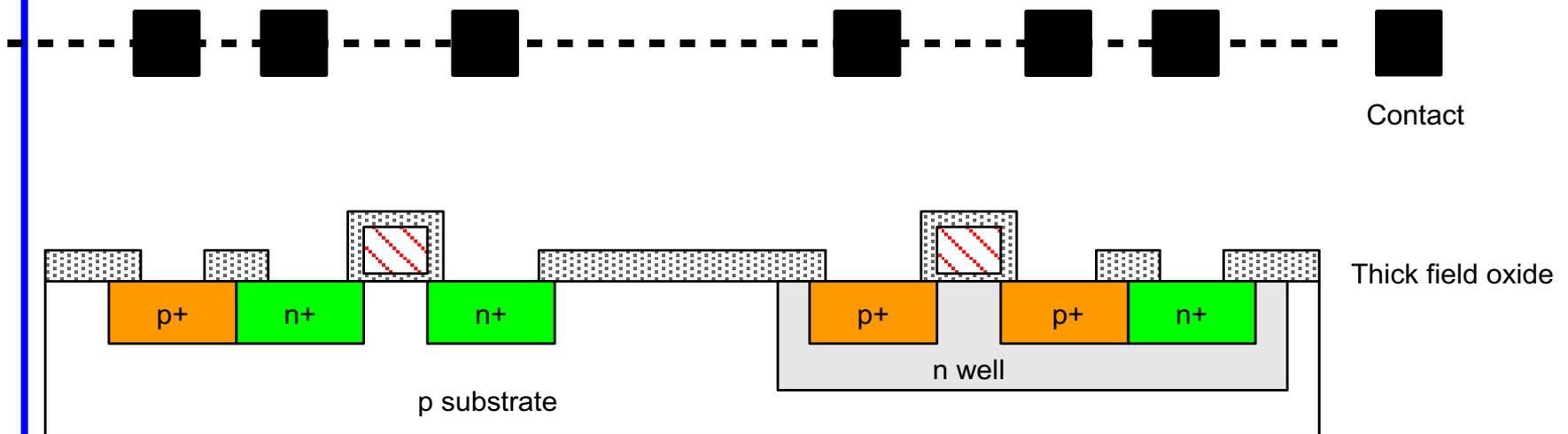
# P-Diffusion

- Similar set of steps form p+ diffusion regions for pMOS source and drain and substrate contact



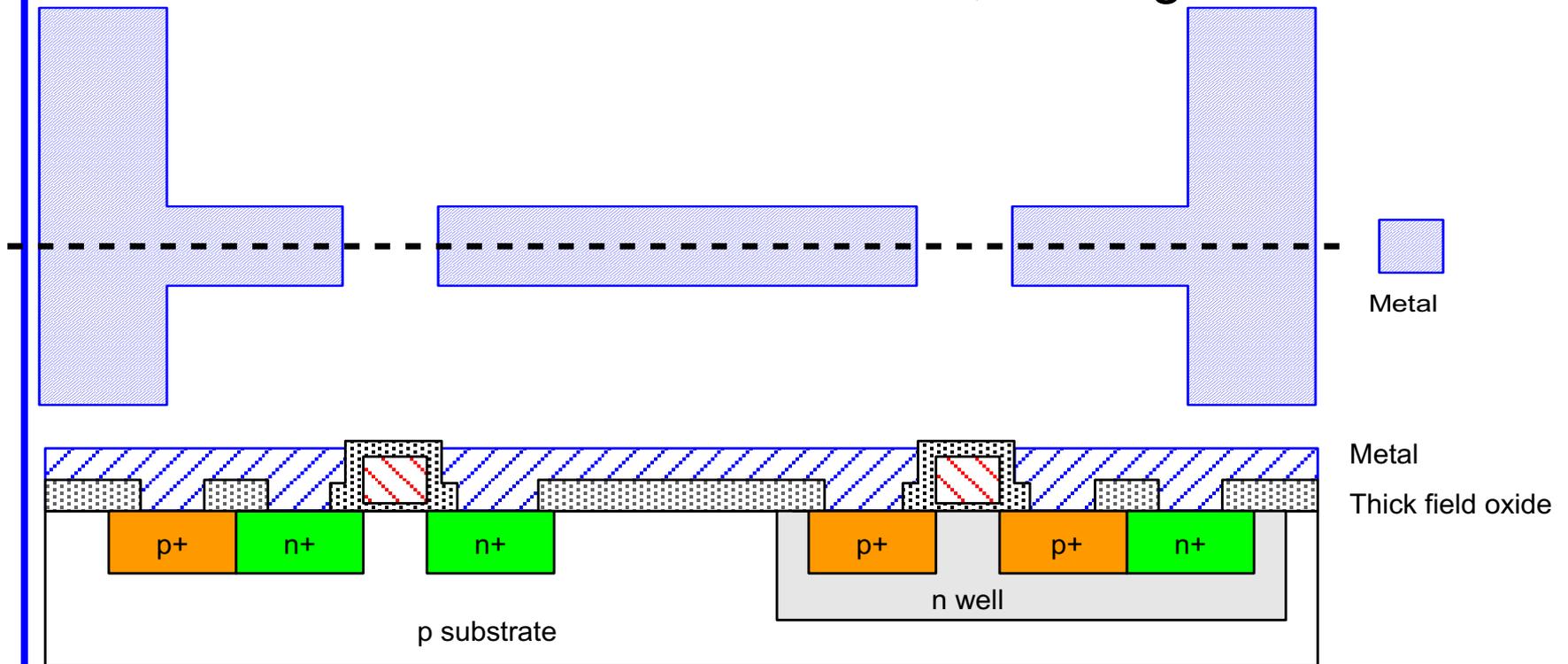
# Contacts

- ❑ Now we need to wire together the devices
- ❑ Cover chip with thick field oxide
- ❑ Etch oxide where contact cuts are needed



# Metalization

- ❑ Sputter on aluminum over whole wafer
- ❑ Pattern to remove excess metal, leaving wires

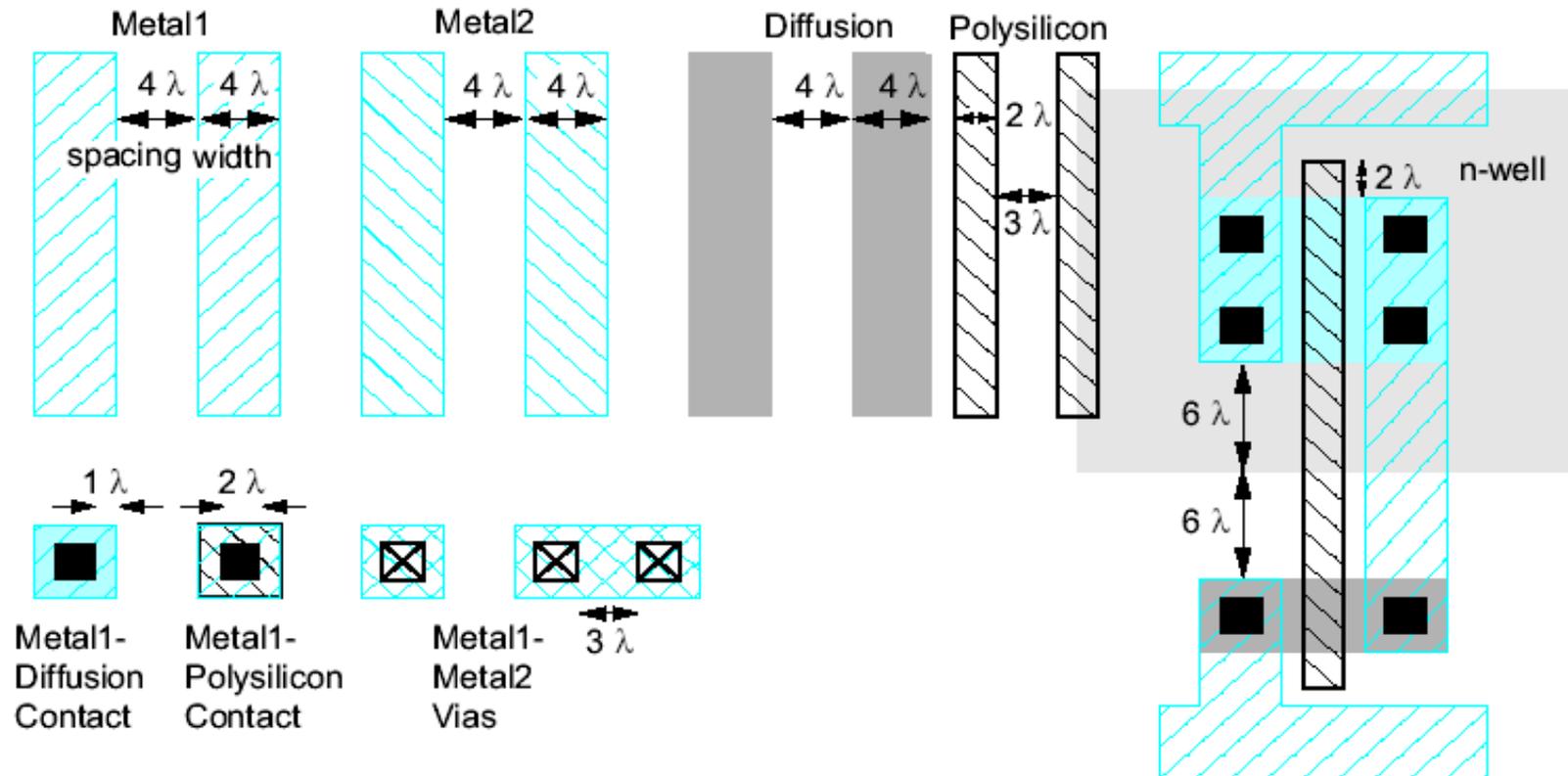


# Layout

- ❑ Chips are specified with set of masks
- ❑ Minimum dimensions of masks determine transistor size (and hence speed, cost, and power)
- ❑ Feature size  $f$  = distance between source and drain
  - Set by minimum width of polysilicon
- ❑ Feature size improves 30% every 3 years or so
- ❑ Normalize for feature size when describing design rules
- ❑ Express rules in terms of  $\lambda = f/2$ 
  - E.g.  $\lambda = 0.3 \mu\text{m}$  in  $0.6 \mu\text{m}$  process

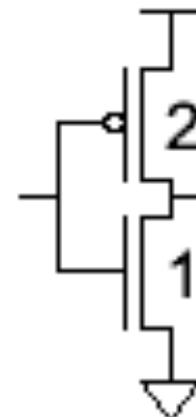
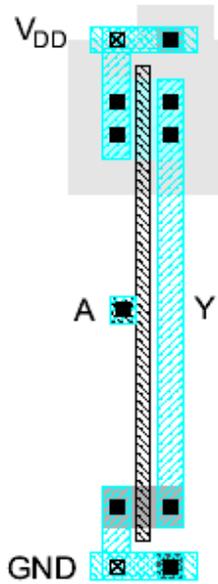
# Simplified Design Rules

- ❑ Conservative rules to get you started



# Inverter Layout

- ❑ Transistor dimensions specified as Width / Length
  - Minimum size is  $4\lambda / 2\lambda$ , sometimes called 1 unit
  - In  $f = 0.6 \mu\text{m}$  process, this is  $1.2 \mu\text{m}$  wide,  $0.6 \mu\text{m}$  long



# Summary

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- ❑ MOS transistors are stacks of gate, oxide, silicon
- ❑ Act as electrically controlled switches
- ❑ Build logic gates out of switches
- ❑ Draw masks to specify layout of transistors
  
- ❑ Now you know everything necessary to start designing schematics and layout for a simple chip!

# About these Notes

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